

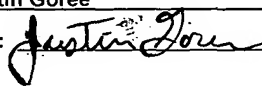
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Serial No. **Not yet assigned**

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For: **SOLID STATE IMAGE SENSOR**

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Transmitted herewith is a certified copy of the
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Bezeichnung der Erfindung/Title of the invention/Titre de l'invention:
(Falls die Bezeichnung der Erfindung nicht angegeben ist, siehe Beschreibung.
If no title is shown please refer to the description.
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Solid state image sensor

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1 "Solid State Image Sensor"

2

3 This invention relates to solid state image sensors
4 with active pixels.

5

6 As is well known, in active pixel image sensors an
7 area of the pixel acts as a photodiode, with photon-
8 generated current being integrated on the self-
9 capacitance of the photodiode. This charge is
10 essentially an analog representation of light
11 received at that pixel during the exposure period.
12 Where a digital signal is desired, it is necessary
13 to provide some means for A-D conversion.

14

15 Most active pixels in current use one or more A-D
16 converters located off the image plane. This
17 maximises the light-converting properties of the
18 image plane, but at the expense of requiring a
19 relatively complex switching or multiplexing
20 arrangement to transfer pixel signals values to the
21 A-D converter(s).

22

1 It has been proposed to use layouts in which each
2 pixel has its own A-D converter; see for example US
3 Patent 5,461,425 (Fowler et al), US Patent 5,801,657
4 (Fowler et al), US Patent 6,271,785 (Martin), and
5 IEEE Journal Solid State Physics, December 2001, Vol
6 36, No 12, p2049 et seq (Kleinfelder et al).
7 However, such prior proposals have the disadvantage
8 that the additional circuitry in each pixel severely
9 reduces the ability of the pixel to collect photo-
10 generated electrons, and thus severely reduces
11 sensitivity.

12
13 The invention is defined in claim 1.

14
15 Preferred features and advantages of the present
16 invention will be apparent from the other claims,
17 and from the following description.

18
19 Embodiments of the invention will now be described,
20 by way of example only, with reference to the
21 drawings, in which:

22
23 Figure 1 illustrates a pixel in a prior art
24 image sensor;

25 Figure 2 is a circuit diagram showing one
26 method of use of the pixel of Figure 1;

27 Figure 3 illustrates a pixel in an image sensor
28 according to one embodiment of the invention;

29 Figure 4 is a circuit using the pixel of Figure
30 3;

1 Figures 5 and 6 are timing diagrams
2 illustrating the operation of the circuit of Figure
3 4;

4 Figure 7 is a timing diagram for a modified
5 form of operation;

6 Figure 8 is a timing diagram showing a further
7 modified mode of operation;

8 Figure 9 shows part of the circuit of Figure 4
9 in greater detail;

10 Figure 10 shows an alternative to Figure 9; and

11 Figures 11, 12 and 13 show modifications to the
12 circuit of Figure 4.

13

14 Figure 1 shows a prior art approach to an image
15 sensor having in-pixel circuitry such as ADC. The
16 sensor is formed on a P-epitaxial layer 12 overlying
17 a P substrate 10. The top part of the P-epitaxial
18 layer 12 is doped to provide the circuit components,
19 namely an N-well 14 forming a collection node, NMOS
20 transistors in a P-well 16, and PMOS transistors in
21 an N-well 18.

22

23 For correct operation, the P-well 16 is biased to
24 Vss (= ground/0V), and the N-well is biased to Vdd,
25 typically 3.3V or 1.8V. The collection node 14 is
26 biased to a voltage between Vss and Vdd.

27

28 Light is absorbed by the silicon at a depth which is
29 wavelength dependent. Typically, visible light
30 generates a substantial proportion of electrons at a
31 depth which is greater than the wells 14,16,18. The
32 collection node 14 as shown in Figure 1 will collect

1 electrons that are generated directly beneath it.
2 Those electrons which are generated close to the
3 border of the collection node 14 and the P-well 16
4 are attracted to the positive potential of the
5 collection node 14 and are collected. However,
6 these electrons which are generated underneath or
7 close to the N-well 18 are attracted to the positive
8 bias of the N-well and are not collected. This
9 corresponds to a loss of sensitivity of the pixel.

10

11 Figure 2 illustrates a circuit of the sensor of
12 Figure 1. One pixel 20 is shown, which includes the
13 collection node 14 shown as the equivalent diode 22
14 and capacitance 24. NMOS transistors M1-M4 control
15 operation of the pixel, as will be described in more
16 detail below. A comparator is formed by PMOS
17 transistors M5-M7 and NMOS transistor M8, giving an
18 output on line 26 when the sampled pixel voltage
19 equals a ramp voltage V_{ramp} on line 28.

20

21 A number of schemes are possible for using the
22 change of state of the comparator. In the example
23 shown, the line 26 sets an N-bit latch 30 according
24 to a 10-bit gray scale. The latch 30 could be
25 inside or outside the pixel. The latch 30 for a
26 given pixel is enabled at the appropriate time by a
27 decode circuit 32. The latch thus outputs a 10-bit
28 representation of the pixel value, in this example
29 to a frame store 33.

30

31 Turning to Figure 3, the invention in this
32 embodiment once again has a P-epitaxial layer 10

1 over a P substrate 10. A collection node 14 is
2 formed as an N-well. The surrounding surface is
3 formed as a P-well 16 with amplification transistors
4 provided by NMOS transistors only. The collection
5 node 14 and P-well 16 may be contiguous, as shown,
6 or may be separated by an insulation or isolation.

7
8 Thus, the sensor of Figure 3 contains no N-well
9 other than the collection node 14. Electrons
10 generated in the epitaxial layer 10 are attracted to
11 the most positive point in the pixel, which is now
12 the collection node 14, thus increasing the
13 sensitivity.

14
15 Figure 4 shows one possible circuit making use of
16 this. As discussed, the pixel 20 contains only NMOS
17 transistors. Transistor M4 is used to reset the
18 pixel voltage. Transistors M1-M3 form a long tail
19 pair, with M1 forming a current source to M2 and M3.
20 The long tail pair is connected to a current mirror
21 formed by PMOS transistors M5 and M6 located off the
22 pixel.

23
24 After reset, the voltage on the gate of M2 is higher
25 than V_{ref} (gate of M3). More current flows through
26 M3 than M2 and hence more through M5 than M6. This
27 keeps the gate of M7 high and the output "Comp_out"
28 low.

29
30 After some time, dependent on the amount of light
31 falling on the pixel, the voltage "Vphotodiode" will
32 be lower than that on the gate of M3. When this

1 happens, more current will flow through M3 than M2
2 and hence more through M6 than M5. This takes the
3 gate of M7 low and the output Comp_out goes high.

4

5 The time that this transition takes place is stored
6 using the N-bit latch 30 (in this example 10-bit).

7 In the arrangement of Figure 4, there is an external
8 current mirror and latch for each pixel. Typically,
9 the outputs of the pixel latches are commoned onto a
10 bus, and an address bus 31 and select circuit 32 are
11 used to enable the bus output.

12

13 Figure 5 illustrates the timing for the circuit of
14 Figure 4. As will be seen at A and B, the greater
15 the amount of light falling on the pixel, the
16 steeper is the slope of the integrating waveform and
17 the earlier the comparator changes state.

18

19 This arrangement has the disadvantage that, as shown
20 at B' in Figure 6, low light levels produce a very
21 shallow slope on Vphotodiode. This can be addressed
22 either by lengthening the integration time, which
23 reduces the speed of the whole system, or by setting
24 Vref very close to the maximum of Vphotodiode, which
25 makes the system very sensitive to noise. Figure 7
26 overcomes these limitations by providing Vref in the
27 form of a piecewise linear ramp C during
28 integration.

29

30 Figure 8 illustrates a further modification for use
31 in mitigating fixed pattern noise. With careful
32 layout, transistors M2 and M3 will match accurately.

1 However, there is likely to be an offset when the
2 outputs from the long tail pair and the current
3 mirror change states. Moreover, because of
4 manufacturing tolerances this offset is likely to
5 vary between pixels, causing fixed pattern noise.

6
7 Figure 8 shows an offset cancellation scheme. Reset
8 transistor M4 is kept closed and the pixel is kept
9 in reset. A ramp D is applied to Vref at the gate
10 of M3. The system operates in a similar manner to
11 the exposure of the pixels: when the comparator
12 changes state the latch stores the count value on
13 the "Gray(0...9)" bus and this count is stored in
14 the frame store for subsequent subtraction from the
15 output of the integration phase.

16
17 In the simplest implementation, the width of the
18 frame store matches the width of the latches and the
19 gray scale counter, i.e. 10 bits in the present
20 example, as seen in Figure 9. However, to save
21 space in the IC it is possible to use a narrower
22 width of frame store and a selector circuit so that
23 only the most relevant 8 bits, for example, are
24 used. This is seen in Figure 10 where a multiplexer
25 36 is used to select the 8 most significant bits if
26 the signal is large, or the least significant 8 bits
27 if the signal is small.

28
29 The foregoing description assumes that each pixel
30 has its own current mirror and latch. This is
31 feasible for small arrays, but for larger arrays it
32 becomes necessary to share the current mirrors and

1 latches between many pixels. In the system shown in
2 Figure 11, the "Bias1" signal to the current load in
3 the long tail pair is used to enable each of the
4 rows in sequence. When Bias1 is low the pixel's
5 readout is disabled, enabling the pixel to set to a
6 suitable level. When Bias1 goes high the long tail
7 pair is enabled and the difference between the
8 photodiode voltage and Vref is output as a current
9 difference on lines 38 and 40. The control signal
10 for Bias1 is added to the address bus PixA(0...9) so
11 that the output from the latch is written into the
12 appropriate memory location.

13

14 For larger arrays, the parasitic effect of the
15 drains from all the pixels in the column will slow
16 access. To avoid this, as seen in Figure 12, NMOS
17 FETs 42 and 44 are inserted at each pixel into both
18 legs of the long tailed pair and are used to
19 multiplex the output onto the lines 38 and 40.

20

21 Alternatively or additionally, cascode transistors
22 46 can be used (as seen in Figure 13) to reduce the
23 effects of stray capacitance on the lines 38 and 40
24 from the pixels.

25

26 The foregoing embodiments have been described in
27 terms of a P-type substrate, with the collection
28 node formed as an N-well and only NMOS transistors
29 within the pixel. In principle, this could be
30 inverted with the substrate N-type, the collection
31 node a P-well and only PMOS transistors within the
32 pixel.

1

2 The invention provides image sensors in which the
3 pixels have greater sensitivity than in the prior
4 art. Also, the pixels have a balanced readout which
5 provides greater noise immunity than in the older
6 analog readout mechanisms.

7

8 Greater sensitivity give a sensor which is able to
9 operate at lower light levels: a significant
10 requirement for cameras. systems which incorporate
11 their own light source require less power to
12 illuminate the pixel, leading to reduced power
13 consumption.

1 CLAIMS

2

3 1. A solid state image sensor comprising a doped
4 single crystal chip, one face of the chip
5 forming an active pixel array; said face being
6 formed on a P substrate by a P-epitaxial layer
7 on which are formed pixels each comprising:

8 an N-well acting as a collection node,
9 one or more P-wells adjacent the N-well,
10 and

11 in-pixel circuit elements comprising as
12 active elements only NMOS transistors in at
13 least one said P-well.

14

15 2. A solid state image sensor as defined in claim
16 1 but with N and P reversed.

17

18 3. An image sensor according to claim 1 or claim
19 2, in which said in-pixel circuit elements form
20 part of an analog-to-digital converter which
21 also comprises circuit elements external to the
22 pixel.

23

24 4. An image sensor according to claim 3, in which
25 said in-pixel circuit elements form an
26 amplifier which is connected, directly or by
27 switching, to a comparator external to the
28 pixel and forming part of the analog to digital
29 converter.

30

31 5. An image sensor according to claim 4, in which
32 the in-pixel circuit elements form a long tail

- 1 pair connected to receive the pixel photodiode
2 voltage and a reference voltage, and providing
3 a balanced output to an off-pixel current
4 mirror which in turn is connected to said
5 comparator.
6
- 7 6. An image sensor according to claim 5, including
8 a counter in which a count is latched by a
9 change of state of the comparator.
10
- 11 7. An image sensor according to claim 6, including
12 a frame store, and in which the count latched
13 in the counter is transferred to the frame
14 store.
15
- 16 8. An image sensor according to claim 5, in which
17 the reference voltage is ramped during the time
18 when the photodiode is integrating photoinduced
19 current.
20
- 21 9. An image sensor according to claim 5 or claim
22 8, in which the reference voltage is ramped
23 during reset of the pixel to provide offset
24 compensation.
25
- 26 10. An image sensor according to claim 6 or claim
27 7, in which each pixel is provided with a
28 respective off-pixel comparator and counter.
29
- 30 11. An image sensor according to claim 6 or claim
31 7, in which a number of pixels in a given row
32 or column share a single off-pixel comparator

1 and counter, said pixels being enabled
2 sequentially.

3

4 12. An image sensor according to claim 11, in which
5 the outputs of the long tail pair in each pixel
6 are multiplexed to a pair of output lines
7 common to said number of pixels.

8

9 13. An image sensor according to claim 11 or claim
10 12, in which cascode transistors are provided
11 in the outputs of each long tail pair.

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14

ABSTRACT (Fig. 3)

"Solid State Image Sensor"

An active pixel image sensor is formed on a P-epitaxial layer (10) on top of a P substrate (12). Each pixel consists of an N-well (14) acting as a collection node and a number of transistors. The pixel transistors comprise only NMOS transistors formed in P-wells 16. Circuits are described in which the in-pixel transistors cooperate with off-pixel PMOS transistors to form ADC circuits.

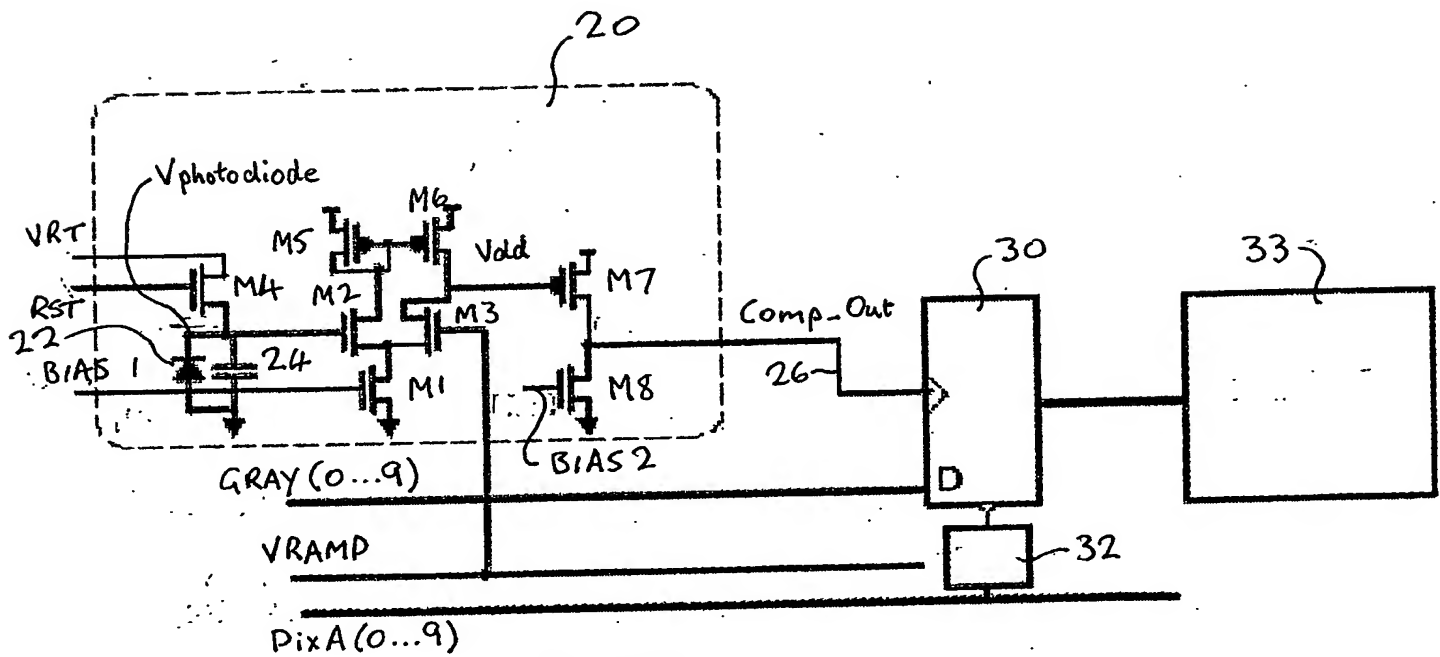
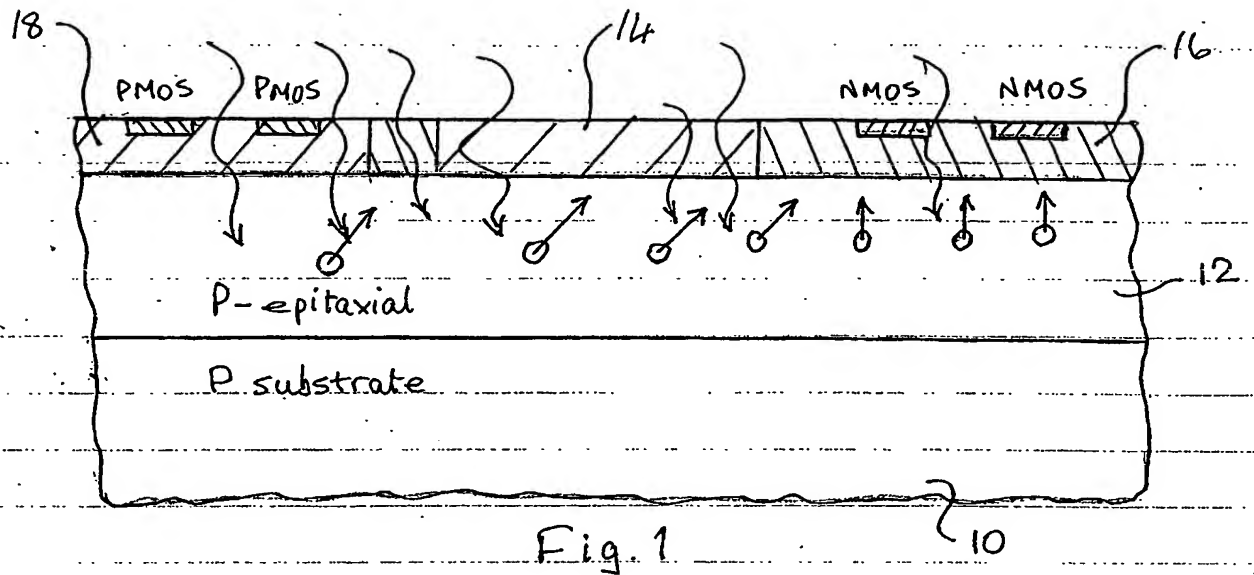


Figure 2

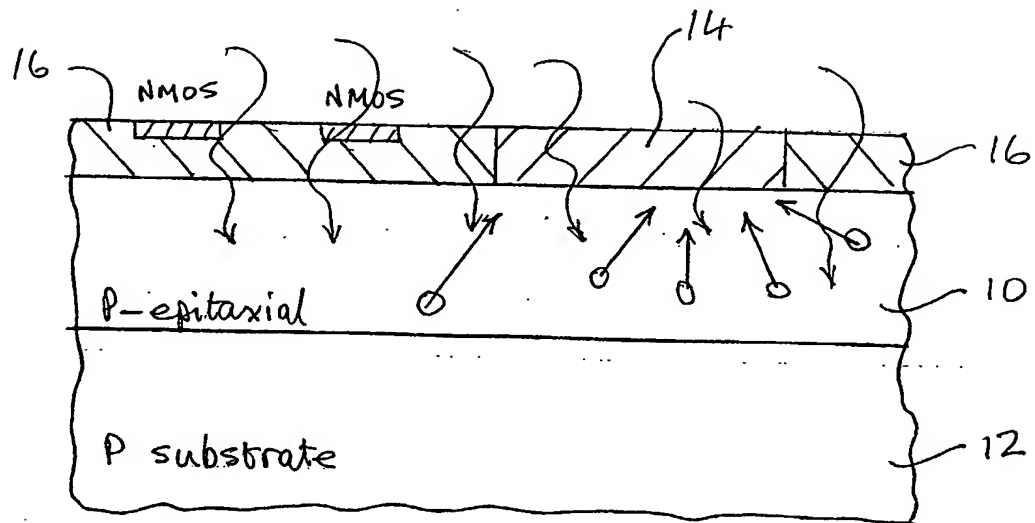


Fig. 3

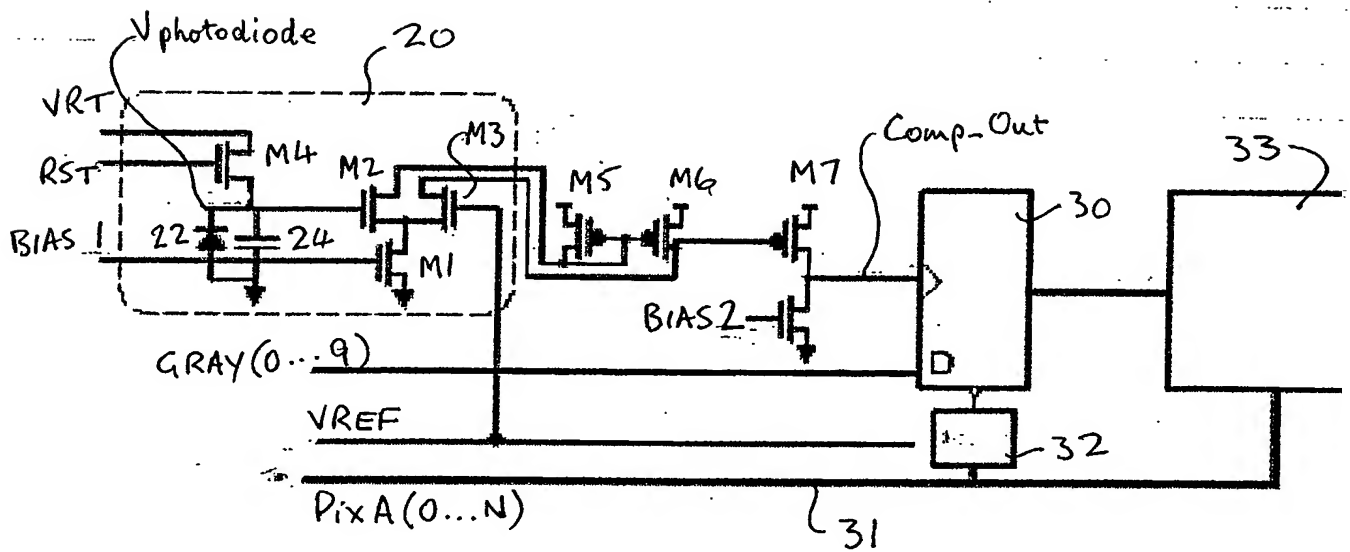


Figure 4

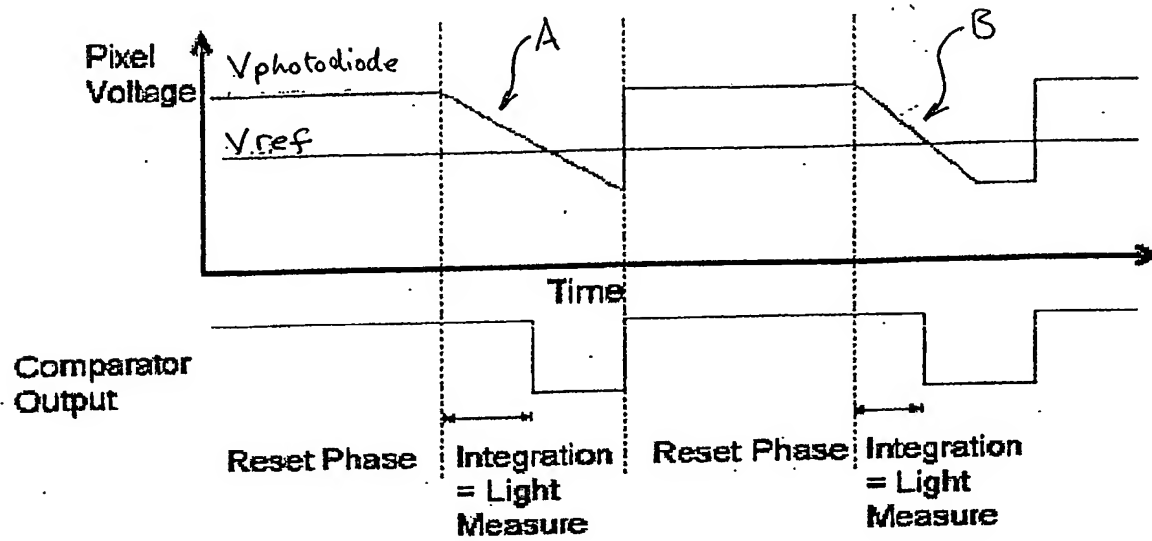


Figure 5

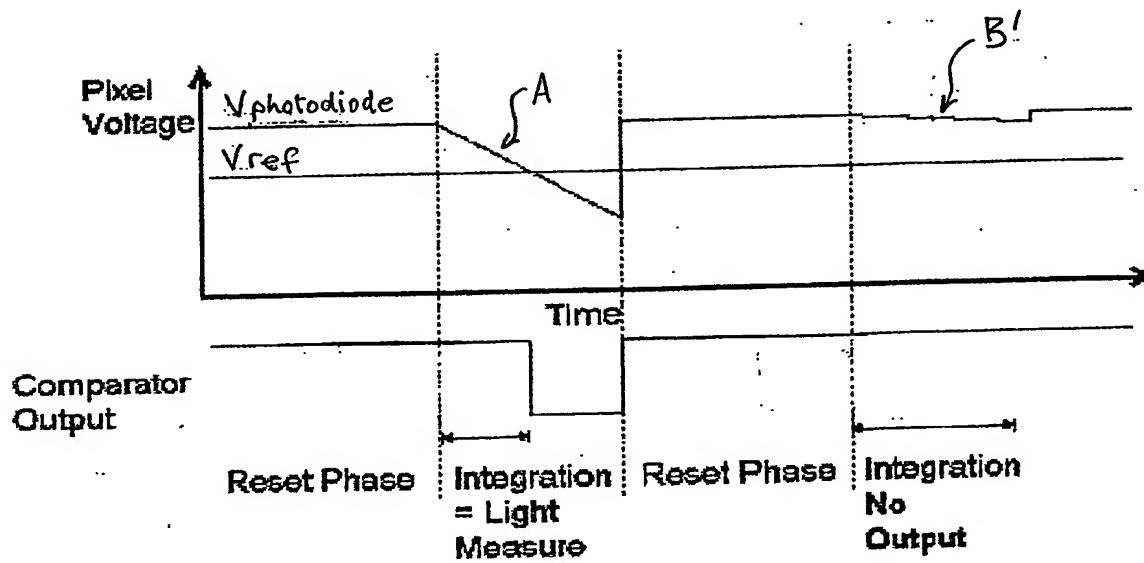


Figure 6

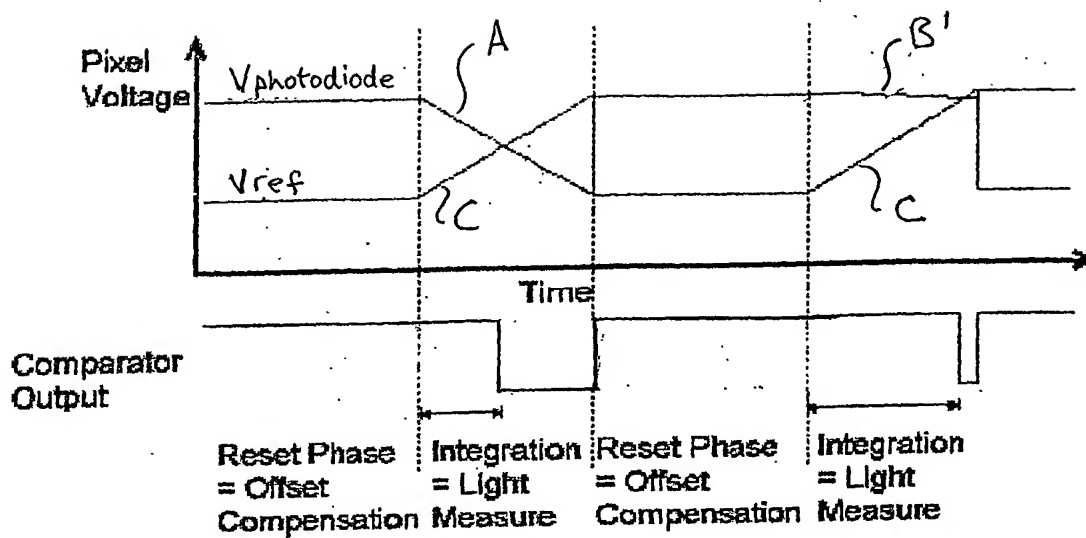


Figure 7

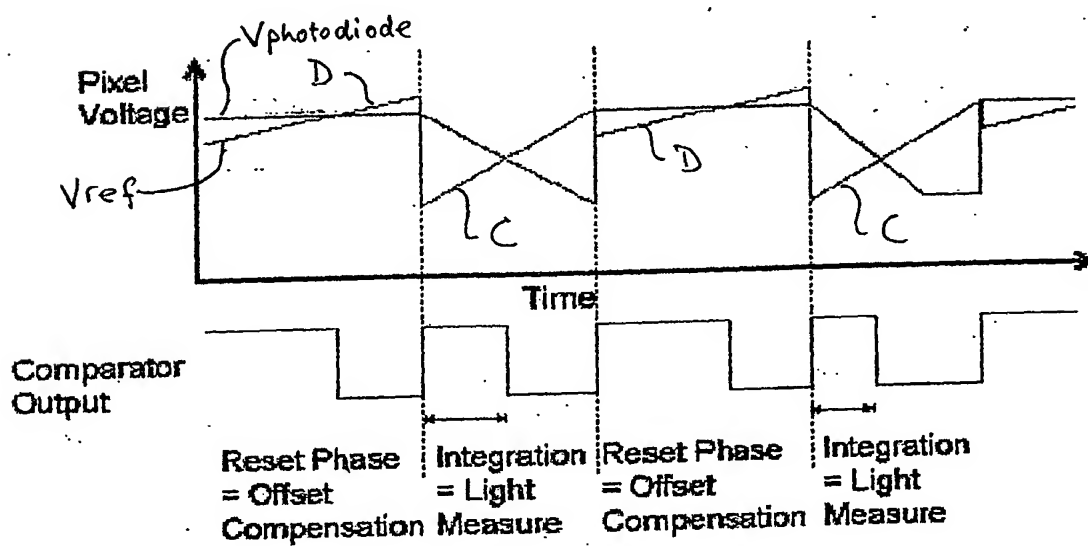


Figure 8

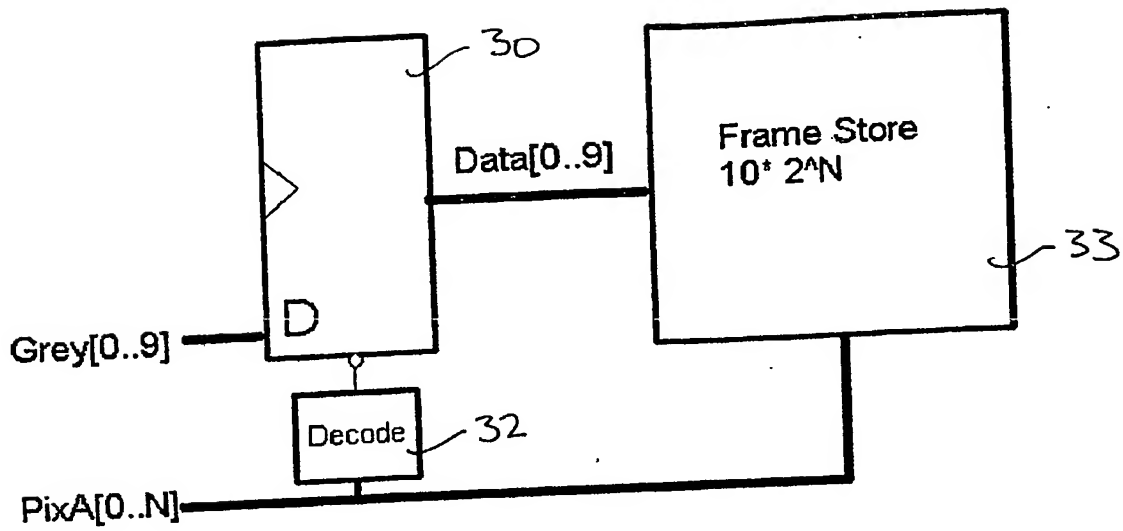


Figure 9

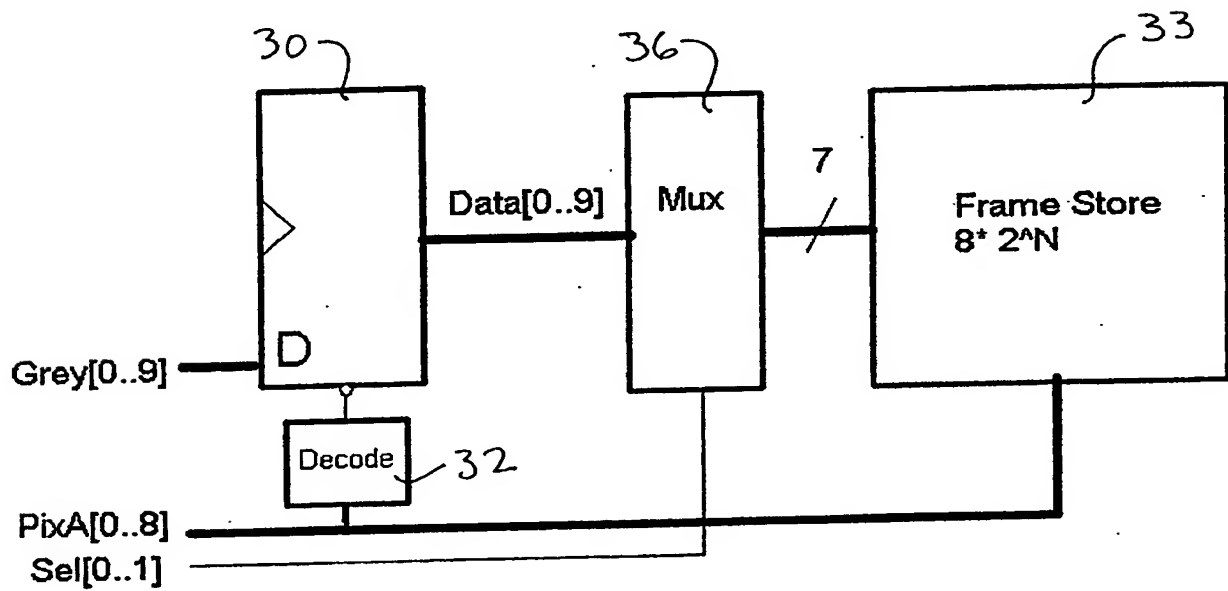


Figure 10

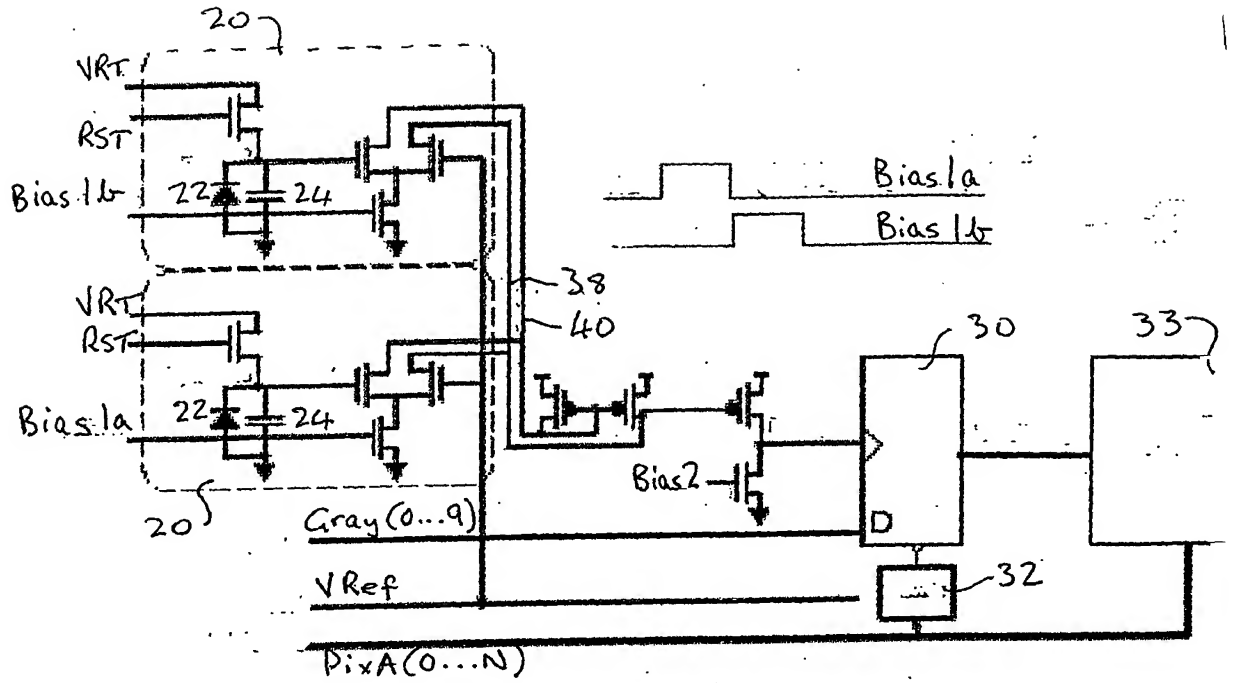


Figure 11

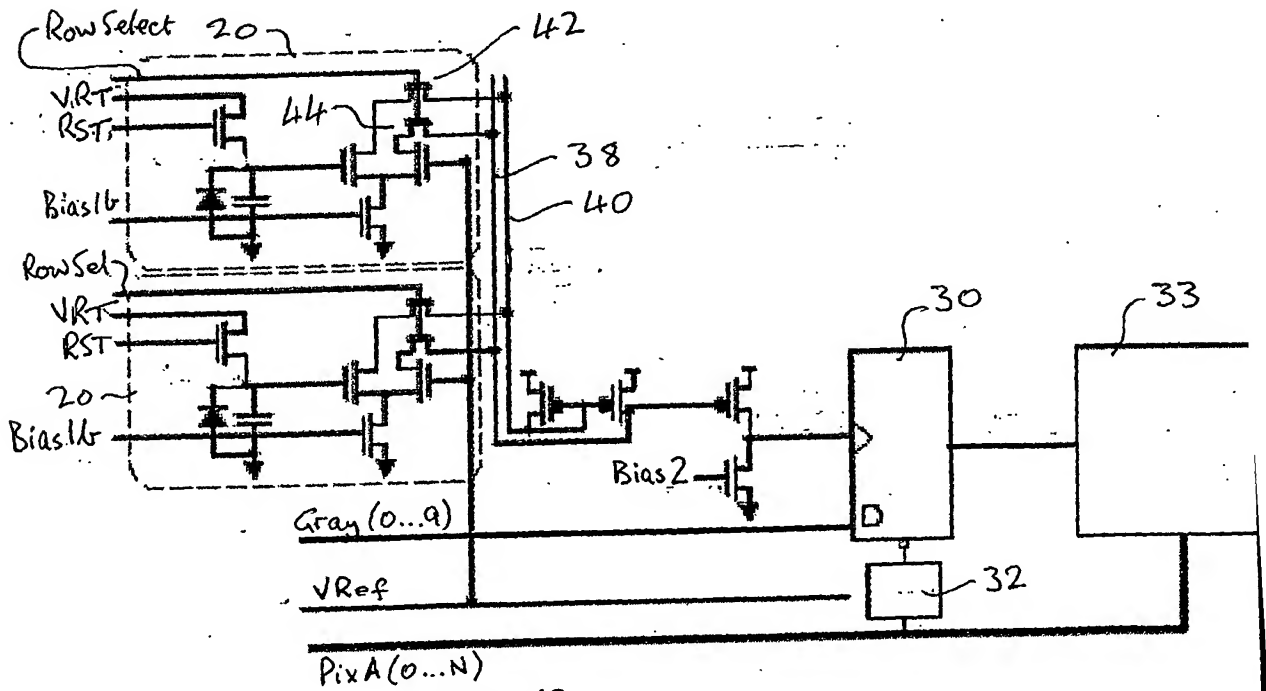


Figure 12

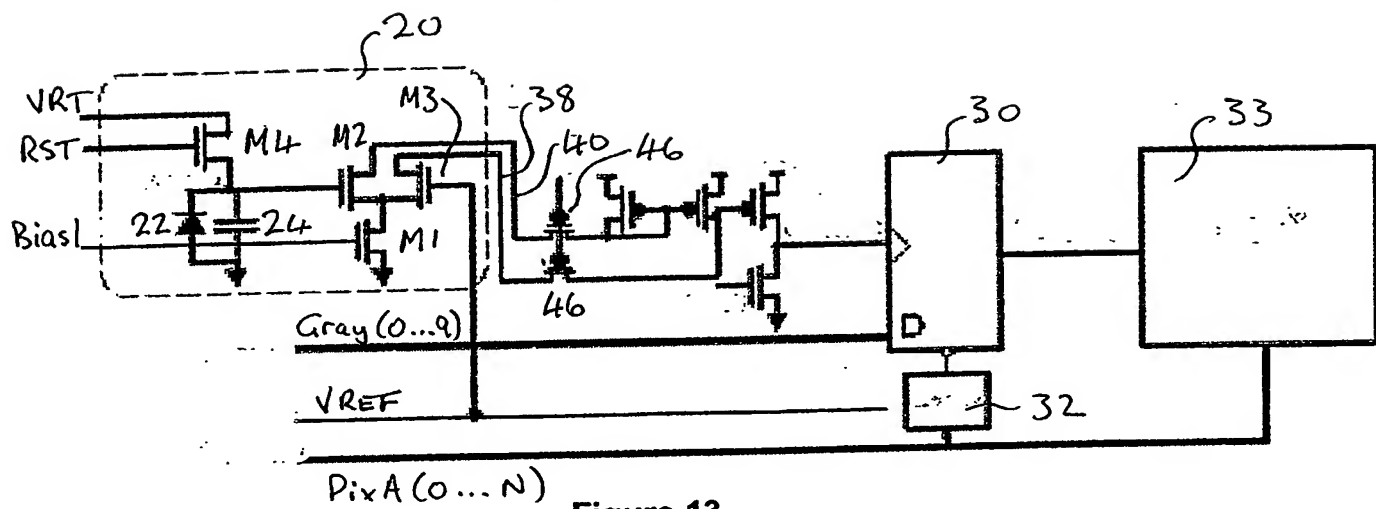


Figure 13

